

# AES PLASMA CUTTING DOWNDRAFT LEV SYSTEM



## DESCRIPTION

The AES series of plasma cutting downdraft benches are fitted with a specific plasma cutting work surface for connection via Ø300mm outlet to a separate FEC NV Cartridge fan/filter unit (specs overleaf).

The benches are available in 4 lengths with multiple benches able to be connected in series to a single filter. Filter systems to match each bench size or qty. can be specified by AES on request.

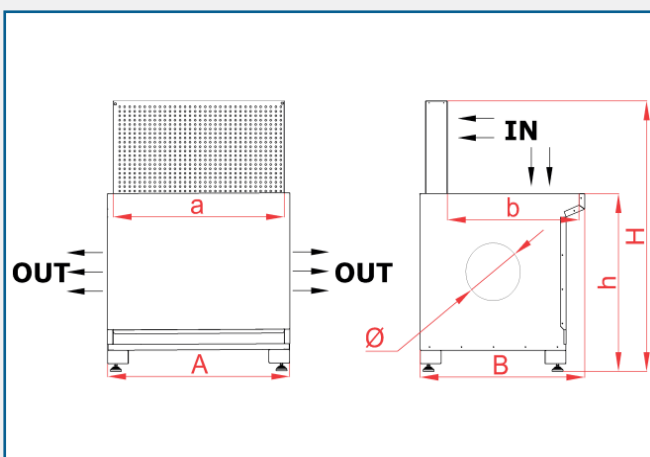
## FEATURES & OPTIONS

- Dust collection drawer
- Side and rear panels (optional)
- Plasma cutting work surface
- Adjustable feet
- Vice base preparation (optional)
- Castors (optional)
- Desk upgrade to 250 kg/m<sup>2</sup>
- Dedicated FEC NV Fan & Filter System

## TECHNICAL SPECIFICATION - BENCH

Model	GEB 10 (PC)	GEB 15 (PC)	GEB 20 (PC)	GEB 30 (PC)
Pressure drop (Pa)	100	100	100	100
Dimensions (A x B x H) (mm)	930 x 900 x 1400	1430 x 900 x 1400	1930 x 900 x 1400	2820 x 900 x 1400
Worktop (a x b x h) (mm)	870 x 715 x 920/960	1370 x 715 x 920/960	1870 x 715 x 920/960	2760 x 715 x 920/960
Outlet (Ø)	300	300	300	300
Maximum load (kg/m <sup>2</sup> )	150	150	150	150
Suggested airflow (m <sup>3</sup> /h)	2000	2700	3300	4800
Suitable filter for standard applications	FEC APT FEC NV DCA GWF	FEC APT FEC NV DCA GWF	FEC APT FEC NV DCA GWF	FEC NV DCA GWF
Suitable filter for plasma cutting for 1 bench	FEC 4 NV	FEC 6 NV	FEC 6 NV	FEC 8 NV

## DIMENSIONS - PC BENCH



## EXAMPLE C/W SIDE & REAR PANEL

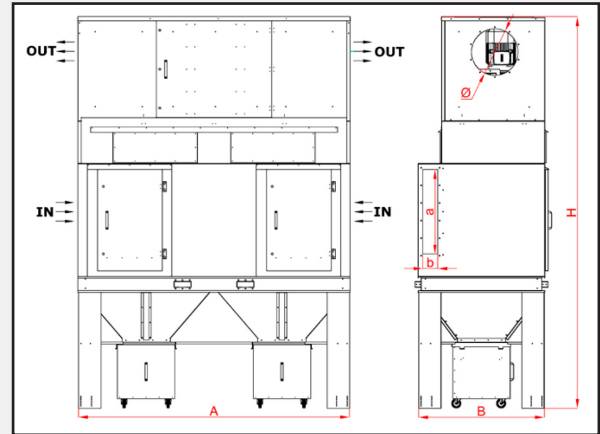


AES OFFER INSTALLATION AND SERVICE SUPPORT FOR ALL EQUIPMENT

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## DIMENSIONS - FEC NV



## TECHNICAL SPECIFICATION - FILTER UNIT FEC NV

Model		FEC 4 NV	FEC 6 NV	FEC 8 NV
Power	kW	To be defined in accordance to fan selection.		
Airflow	m <sup>3</sup> /h	4,000	6,000	8,000
Available pressure	Pa	To be defined in accordance to fan selection.		
Cartridges	No.	4	6	8
Filter surface	Area (m <sup>2</sup> )	80	120	160
Filter efficiency	%	99%		
Dimensions	A x B x C (mm)	900 x 1350 x 3730	1350 x 1350 x 3980	1800 x 1350 x 4180
Inlet	No. Dimension axb	No. 1 450 x 160 mm	No. 1 600 x 160 mm	No. 1 750 x 160 mm
Outlet	No. Ø (mm)	No. 1 350	No. 1 450	No. 1 500
Bin	No. Volume (L)	No. 1 67 L	No. 1 210 L	No. 1 210 L
Suitable bench	Model	GEB 10 (PC)	GEB 15 & 20 (PC)	GEB 30 (PC)

### FEC NV CARTRIDGE FILTER

The FEC NV is designed for a range of industrial processes and is widely used for the extraction of dust and fumes in applications like manual plasma cutting where consistent extraction is needed across the working surface of a bench.

AES have designed a specific plasma cutting extract system that can be configured to meet any work surface size requirement.

The range of cartridges available is not limited to the above, however these have been selected to achieve suitable airflow and face velocity at each of the standard plasma bench sizes.

### FEATURES & OPTIONS

- Large single working surface for plasma cutting
- plasma top allows effective working area and efficient downdraft extraction from the table surface
- Switch for fan control and cleaning operations
- Automatic reverse jet cleaning of cartridge filters
- Collection tray at bench
- High efficiency cartridges
- Bin balance system (optional)
- Collection bin of 67 - 210 L
- Finish in painted RAL colour of your choice
- Fire suppression system (optional)
- Easy maintenance with front loading filter doors and easily accessible fan chamber.

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